

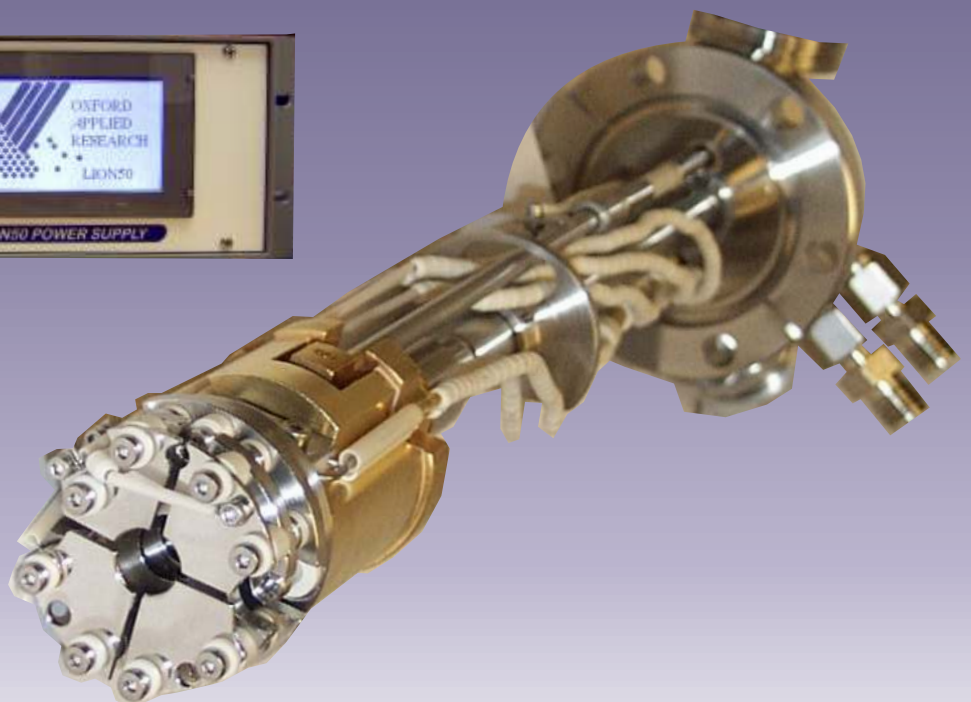
Low Energy Ion Source- Llon50

Specimen cleaning, Ion spectroscopy. 30eV - 1keV

The Llon50

The Llon50 is a low energy gas ion source which operates on the principle of electron impact ionisation. It is capable of producing ion beams with energies between 30eV and 1keV with very narrow energy spread. The source is compatible with a variety of gases, including reactive gases such as O_2 . Applications include ion spectroscopy, particle detection/ calibration and substrate cleaning.

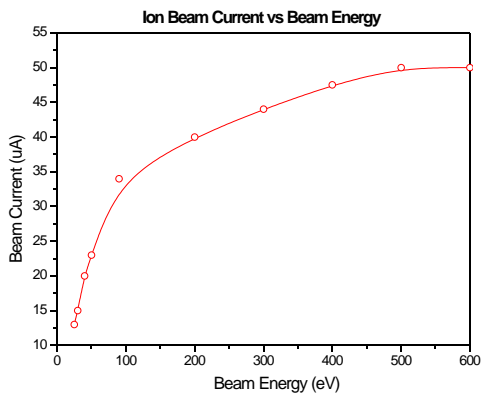
Ions are produced by low-damage electron-impact. The primary electron current is subject to ionisation enhancement processes, which allow up to $30\mu A$ beam current to be generated at 100eV. The instrument incorporates highly efficient water cooling to ensure minimal outgassing during operation.



Low Energy Ion Source

Applications

- Ion spectroscopy
- Particle detection/calibration
- Substrate cleaning
- Surface modification
- Reactive ion etching



Features

- Low ion-beam energy
- Narrow energy spread
- High ion-beam current
- Ultra-clean operation
- Spare filament
- Optional remote control via USB interface

Specifications - LIon50

Mounting flange	NW35CF
In-vacuum diameter	34mm
In- vacuum length	200mm (standard)
Ion beam energy	30eV -1keV
Total beam current	>30µA*
Ionising beam current	200mA (Max.)
Operating gas flow	0-0.5sccm
Beam divergence	15° typical
Services	0.5 litres/min water cooling
Power supply	Single phase 110/220V AC

* Gas and beam energy dependent. Value is for Ar at 0.1kV beam energy

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